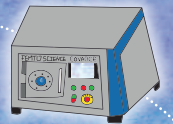
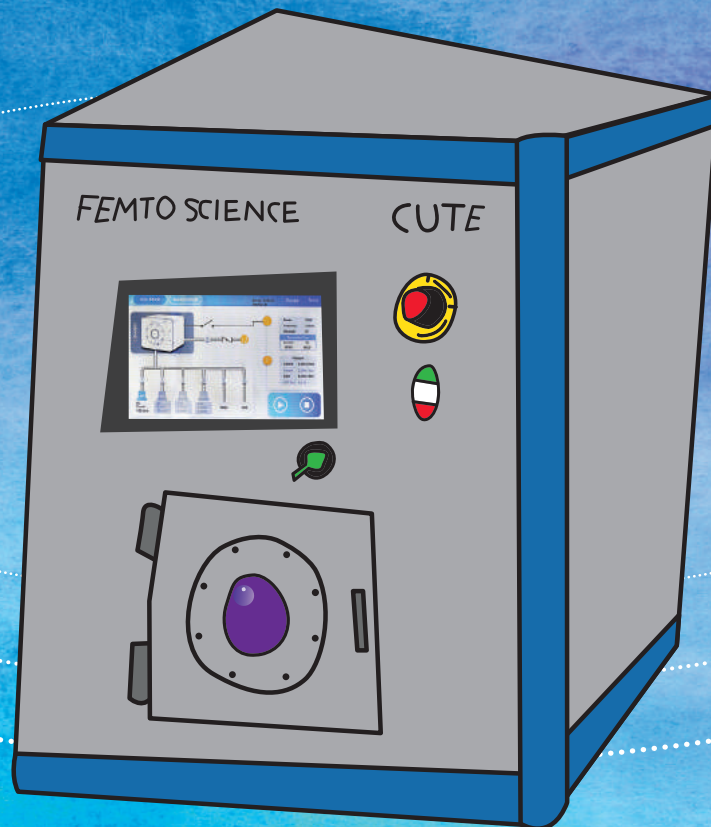




Plasma Processing System

CUTE · COVANCE · COGRADE



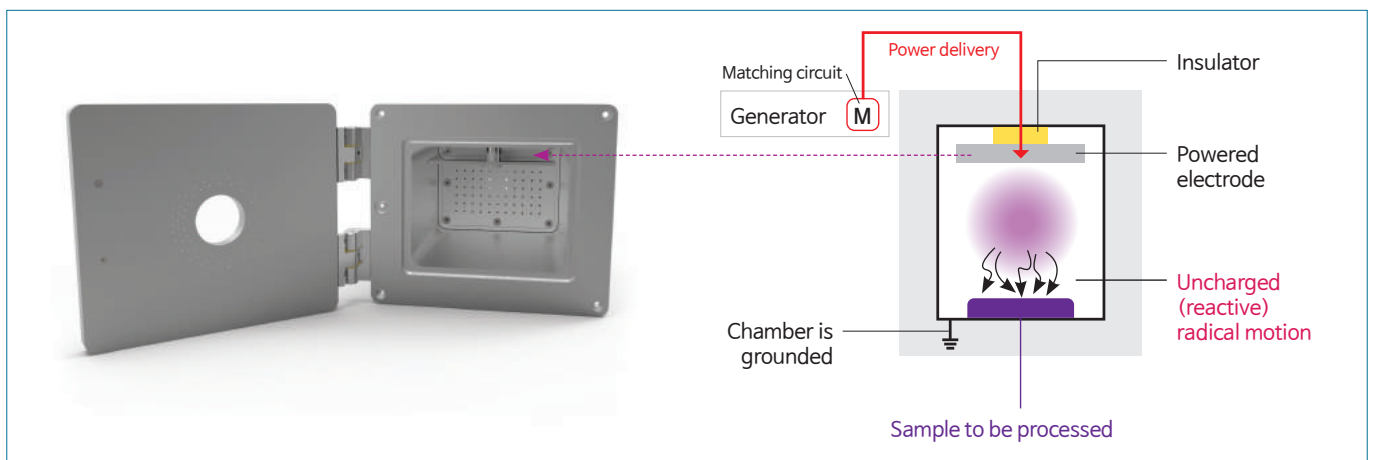
FEMTO SCIENCE



Specification

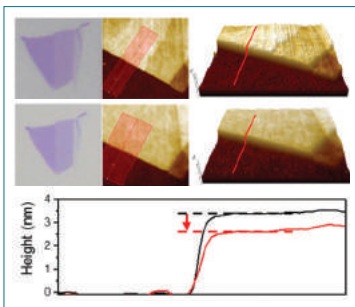
Model	CUTE	COVANCE	COGRADE
Process Mode	PE MODE	PE MODE	PE MODE
Chamber	W.140 x D.200 x H.110 (mm)	W.200 x D.220 x H.160 (mm)	W.250 x D.300 x H.200 (mm)
Generator	20~100kHz Max. 100W	20~100kHz Max. 200W	20~100kHz Max. 300W
MFC	Max. 100 sccm	Max. 200 sccm	Max. 500 sccm
Gauge Pressure	Atm ~ 5×10^{-4} Torr	Atm ~ 5×10^{-4} Torr	Atm ~ 5×10^{-4} Torr
Operation	Manual & Automatic	Manual & Automatic	Manual & Automatic
Geometry	W.440 x D.500 x H.560 (mm)	W.510 x D.525 x H.640 (mm)	W.600 x D.615 x H.680 (mm)

PE Mode

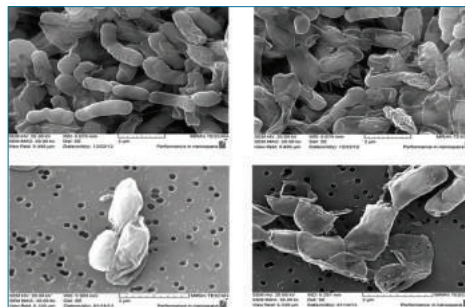


Sample is loaded on electrically grounded surface (connected to chamber wall)

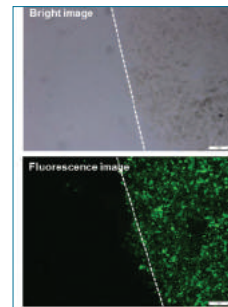
Applications



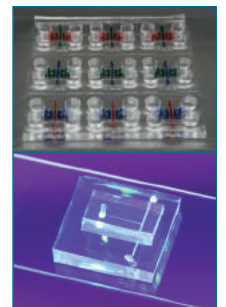
Etching of Graphene



Sterilization



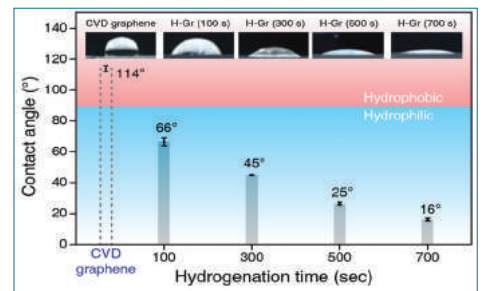
Cell Culturing on Graphene



Microfluidics



Plasma Treatment on Seeds : productivity



Hydrophilicity of Graphene



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